

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Daisuke KOMADA et al.**

Group Art Unit: 1756

Serial No.: 10/058,426

Examiner: **Nicole M. Barreca**

Filed: **January 30, 2002**

Confirmation No.: 4298

For: **METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE
HAVING SILICON CARBIDE FILM**

Attorney Docket Number: 020060

Customer Number: 38834

PETITION FOR WITHDRAWAL FROM ISSUE UNDER 37 CFR §1.313(c)(2)

OFFICE OF PETITIONS

Mail Stop 313(c)

Commissioner for Patents

P.O. Box 1450

Alexandria, Virginia 22313-1450

December 21, 2004

Sir:

It is respectfully requested that the present application be withdrawn from issue for consideration of a Request for Continued Examination and the attached submission of an Information Disclosure Statement.

A Request for Continued Examination and an Information Disclosure Statement are submitted concurrently herewith.

In the event this paper is not considered to be timely filed, the Applicants hereby petition for an appropriate extension of the response period. Please charge the fee for such extension and any other fees which may be required to our Deposit Account No. 50-2866.

Respectfully submitted,

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Attachments: Request for Continued Examination (RCE)

Information Disclosure Statement (IDS) w/ PTO-1449 Form